



## CALL FOR PAPERS

### “Advances in Microelectromechanical Systems”

**The Theme:** Microelectromechanical systems (MEMS) research is a scientific and technological discipline that deals with devices whose characteristic dimensions lie in the range of micrometers, and that is now reaching maturity. After developing the concepts and studying fabrication processes, MEMS researchers have created devices for particular applications that are being successfully applied in the industrial, commercial, defense or aerospace sectors. Newly developed techniques for solving challenging problems are now appearing, as existing and new MEMS devices are combined into complete microsystems. This special section will focus on recent advances in MEMS devices and systems, and related technologies intended to be applied in traditional or new applications. Examples of such applications include: aerospace, automotive, biomedical systems, chemical analysis, energy production and storage, measurement and control, optical or acoustic devices, and many more.

Papers submitted for publication should explain how the presented device or microsystem will help in solving one particular problem, and must present a novel device concept, fabrication process, or design methodology. Topics that can be accepted include but are not limited to:

- Design of microsensors, microactuators, and microstructures
- CAD and modeling of the above
- Fabrication processes and techniques
- Microphenomena and scaling laws
- Applications of MEMS to industrial or other processes or services
- Interfacing microsystems with electronics
- Microrobotics and micromechatronics
- Process control and optimization for mass production of MEMS devices
- Reliability of MEMS devices
- MEMS devices used to improve industrial processes

#### Manuscript Preparation and Submission

Follow the guidelines in “Information for Authors” in the IEEE Transaction on Industrial Electronics <http://tie.ieee-ies.org/tie/> Please submit your manuscript in electronic form through Manuscript Central web site: <http://mc.manuscriptcentral.com/tie-ieee>. On the submitting page #1 in popup menu of manuscript type, select: SS on Advances in Microelectromechanical Systems

#### Timetable

<b>Deadline for manuscript submissions</b>	<b>May 1, 2008</b>
<b>Information about manuscript acceptance</b>	<b>August 2008</b>
<b>Estimated publication date</b>	<b>December 2008</b>

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